

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Sylvia H. Pas

Art Unit: 1763

Division of Serial No.: 09/758,610

Examiner: Karla A. Moore

Filed: Herewith

Docket: TI-22398.1

For: System and Method for Integrated Oxide Removal and Processing of a Semiconductor Wafer

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

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Karen Vertz

Karen Vertz

9-5-03

Date

**PRELIMINARY AMENDMENT**

Dear Sir:

Prior to the examination of the above-identified application, please amend as follows:

**IN THE SPECIFICATION:**

Please amend the Specification by inserting before the first line the following sentence:

--This is a division of Application No. 09/758,610, filed 01/11/2001, the entire disclosure of which is hereby incorporated herein by reference--.